



Dec 2020 Electron microscopy

Detectors







Recording Images In Electron Microscopy

A little bit of history

- Oldest recording medium: photographic film
- 1970: Charge coupled device (CCD) was invented
- 1976: CCD camera was used for astronomy
- 1982: 100 x 100 CCD was directly exposed to 100 kV electrons...radiation damage
- 1988: 576 x 382 CCD used with scintillator and optical coupler
- 1990: Gatan made the world's first commercial CCD camera
- 2002: 128 x 128 direct detection camera developed
- 2008 2009: commercial complementary metal-oxide semiconductor (CMOS) cameras and radiation hard CMOS cameras were introduced



Image & pixels

Thus, the so-called Nyquist limit is defined as the maximum frequency of a signal that can be reproduced at a certain sampling rate (->), i.e. what we can reproduce at best at that sampling rate. This theoretical maximum possible is one pair of lines for every 2 pixels.

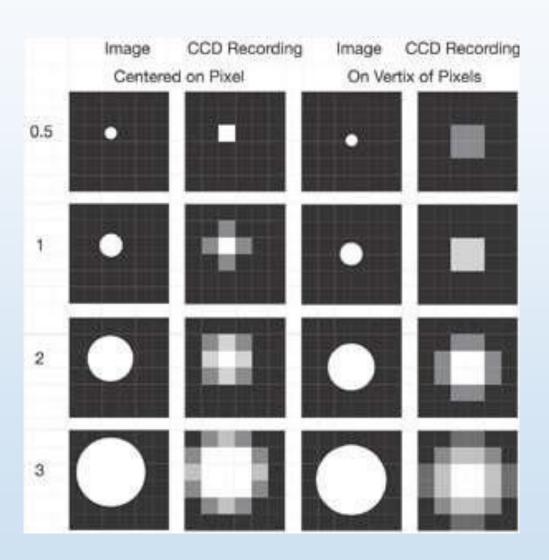
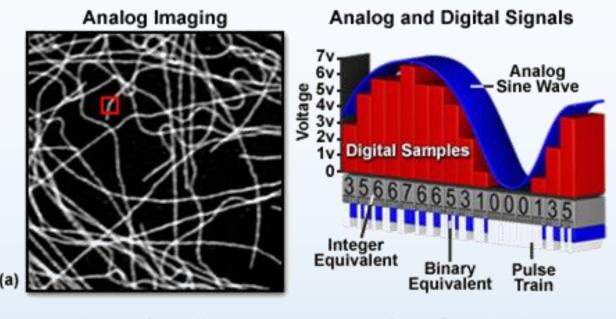
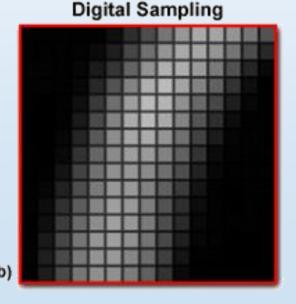
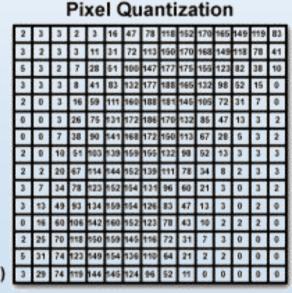


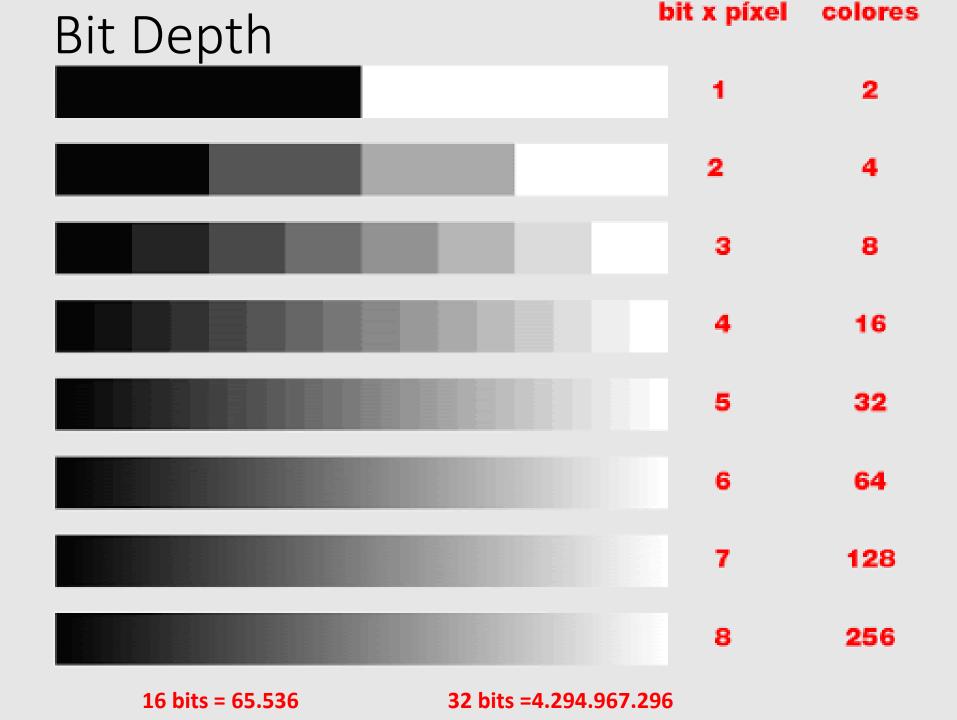
Image & pixels

- It is possible to produce an image from a discrete signal.
- A digital image is not more than a matrix.





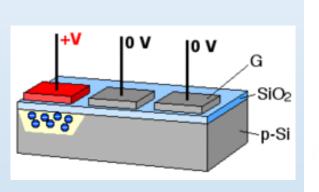


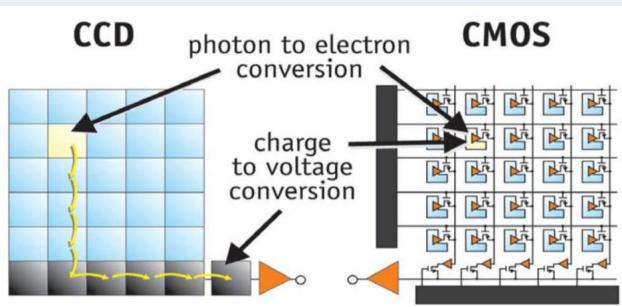


CCD vs. CMOS

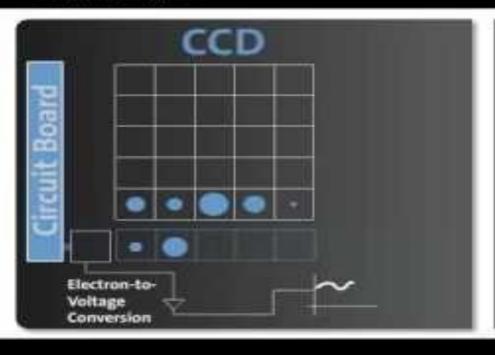
Both CCD and CMOS use photo diodes to convert photons to electrons, the difference is how they store charge and transfer it.

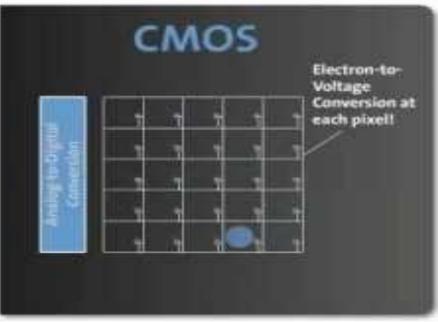
- CCD: Charge is transferred between neighboring cells, and read-out
- CMOS: Charge immediately converted to voltage (read out with digital output)





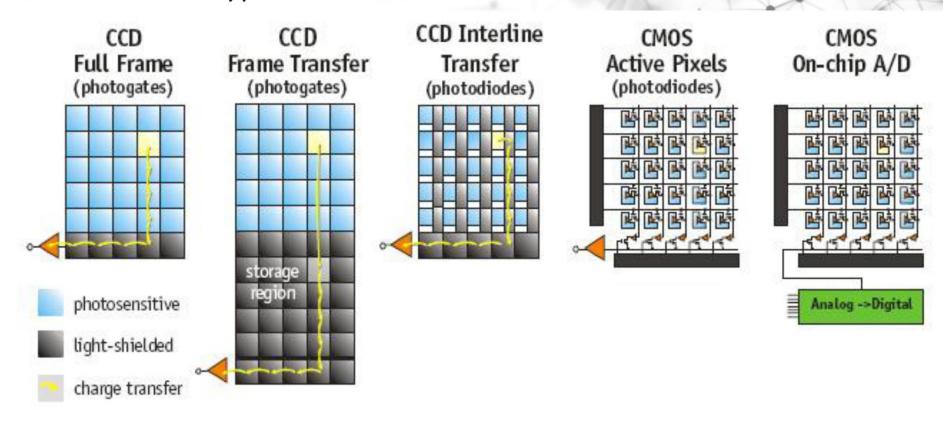
CCDs move photogenerated charge from pixel to pixel and convert it to voltage at an output node. CMOS imagers convert charge to voltage inside each pixel.





CCD and CMOS types

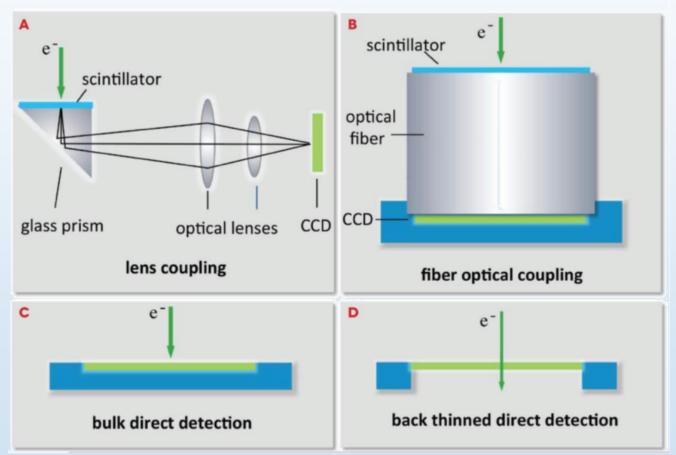
Higher fill factor



Higher complexity

Detectors in Electron Microscopy

- A. Optically coupled
- B. Fiber-optic coupling
- C. Direct detection
- D. Transmission direct detection



Transmission Direct Detection

- Convert electrons to light
- 2. Transfer light to detector
- Detect electron and convert to signal



scattered electrons that add noise

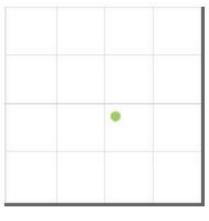
Radiation hard, thinned CMOS



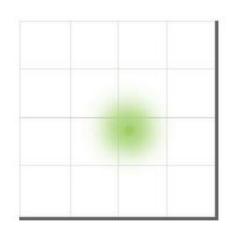
Minimize back

e-

SISTEMA LINEAL O INTEGRATIVO

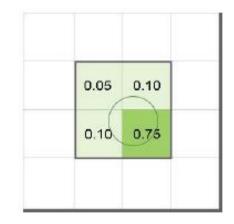


Electron enters Detector.



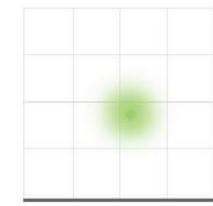
Electron signal is scattered.

CONTEO

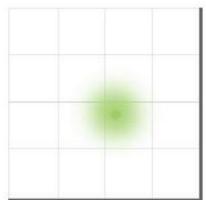


Charge collects in each pixel.

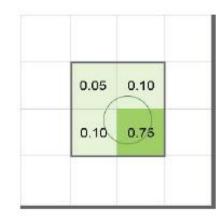
Super-RESOLUCION



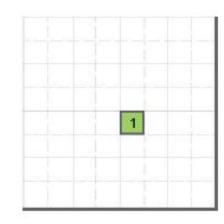
Electron enters Detector.



Electron signal is scattered.

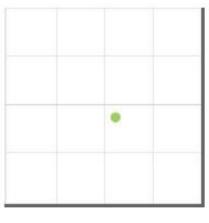


Charge collects in each pixel.

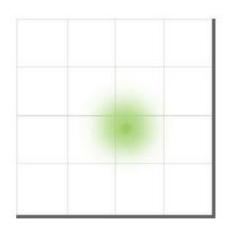


Event localized to sub-pixel accuracy.

SISTEMA LINEAL O INTEGRATIVO

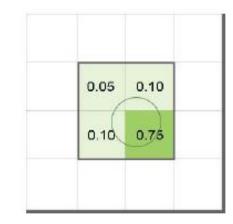


Electron enters Detector.



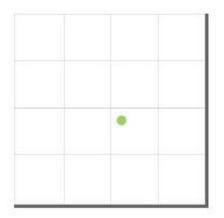
Electron signal is scattered.

CONTEO

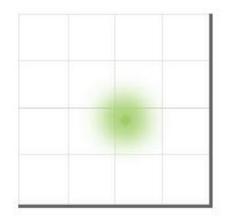


Charge collects in each pixel.

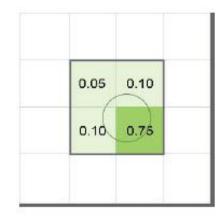
Super-RESOLUCION



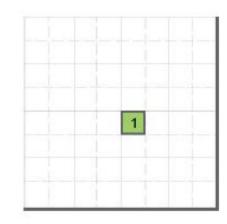
Electron enters Detector.



Electron signal is scattered.



Charge collects in each pixel.

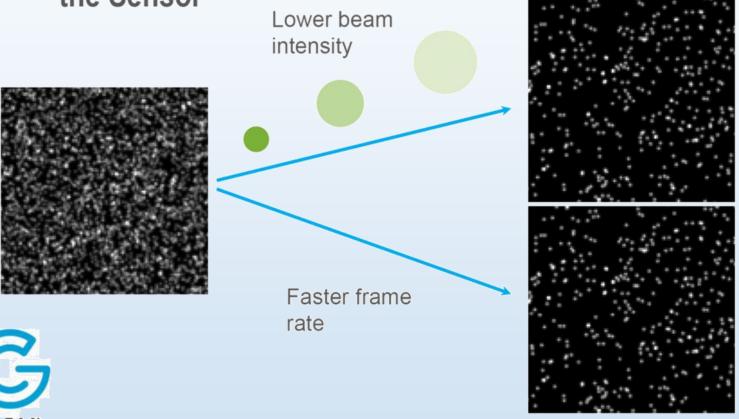


Event localized to sub-pixel accuracy.



Electron Counting Requires that Electrons Don't Overlap on

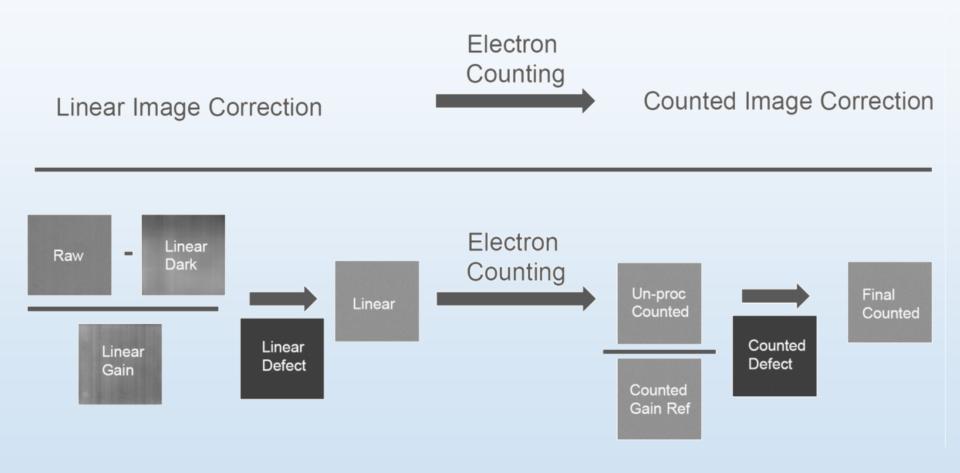
the Sensor



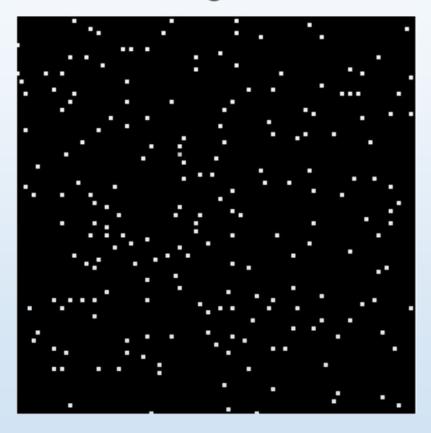
Both methods allow counting, but the effect is not equivalent!



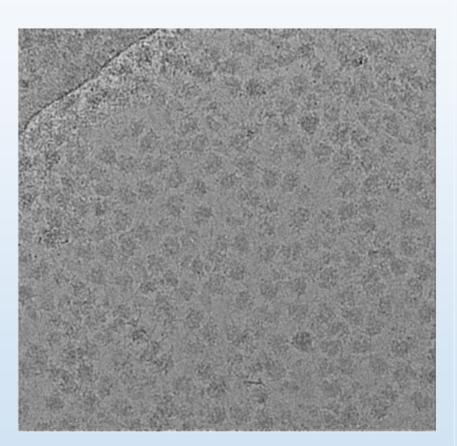
Counted Gain Correction Scheme



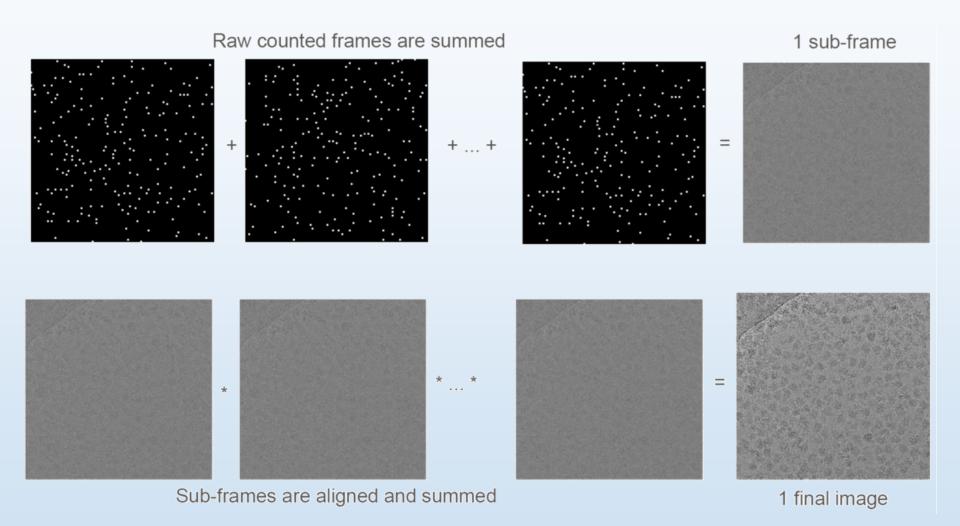
How Frame Alignment Works

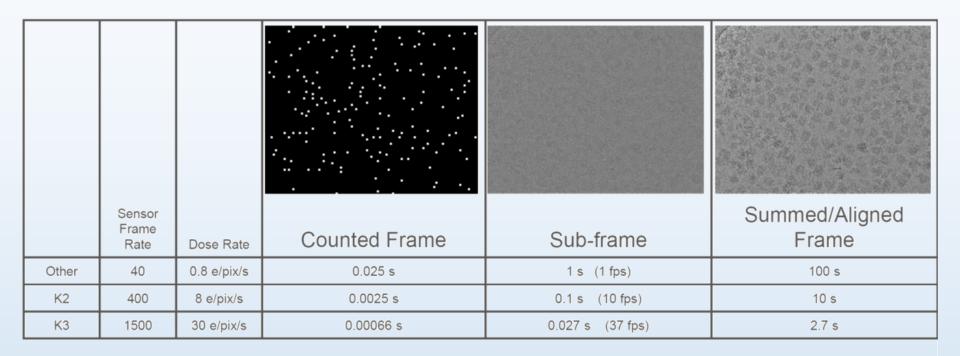


Raw counted frame



Final aligned image







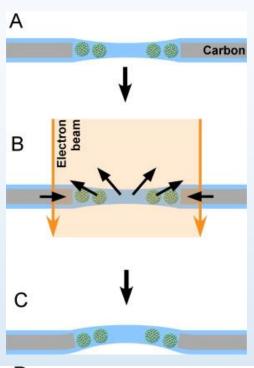


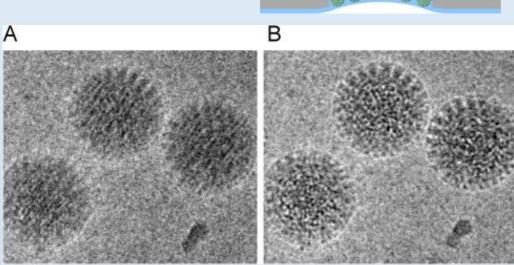


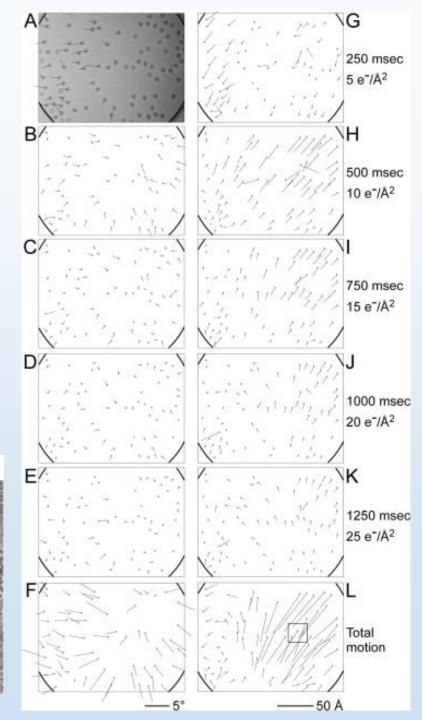


Frame alignment.

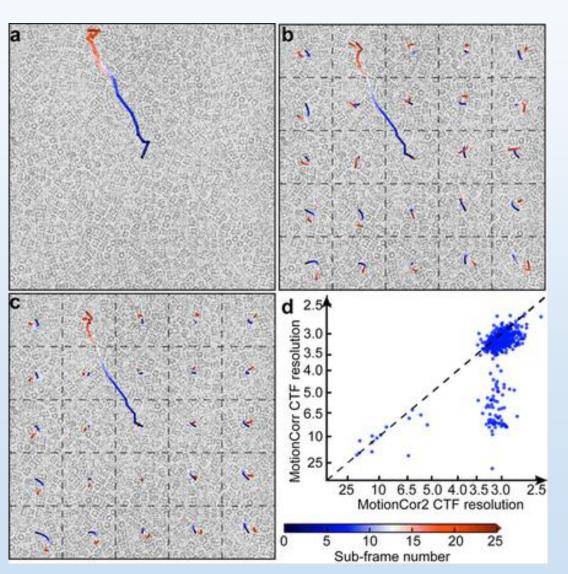
The way to correct
Beam Induced
Movement.
This type of process
are always present
and almost random.

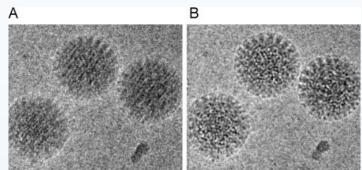






Frame Aligment





Motion correction of cryo-EM images by MotionCor2.(a) Image of frozen hydrated archaeal 20S proteasome overlaid with the traces of motions determined. The long trace originated from the center of image is the global motion based upon full-frame alignment. The whole frame is divided into 5 × 5 patches, and traces of each patch are predicted from the polynomial function. (b) The same image overlaid with the motion traces of each patch as determined from MotionCor2. (c) The trace of globe motion determined from the same image using the original MotionCorr. (d) Resolutions of micrographs estimated using CTFFIND4 22 from the correction by both MotionCorr (vertical axis) and MotionCor2 (horizontal axis). Circles on the lower right side of the dashed line represent micrographs which MotionCor2 produced better correction.